

Nano4me.org Video Download

ESC 212: Basic Nanotechnology Processes

Unit 2: An Introduction to Uses of Plasmas in Processing



Lecture 5

Length: 48:38

This video will cover:

- Analysis of Reactive Ion Etching (RIE)
- Controlling Etch Profile
- Etch Selectivity
- Examples of Making Nano Structures with RIE Techniques

Thank You For Watching!

What did you think? [Email](#) Bob Ehrmann with your feedback.

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